

ABSTRACT

An optical micro-electromechanical device includes a substrate and a mirror assembly suspended above the substrate. The mirror assembly includes a torsional beam and a cantilever. The cantilever includes a cantilever first end and a cantilever
5 second end. The cantilever first end is attached to the torsional beam. The cantilever second end supports a mirror head. A connector is attached to the torsional beam. A counterweight is attached to the connector.